Electronic Acknowledgement Receipt				
EFS ID:	1374095			
Application Number:	10750023			
International Application Number:				
Confirmation Number:	9344			
Title of Invention:	Chemical vapor deposition apparatus			
First Named Inventor/Applicant Name:	Ho Lee			
Customer Number:	32605			
Filer:	Hugh Hakushu Matsubayashi/Pam Disney			
Filer Authorized By:	Hugh Hakushu Matsubayashi			
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Application Type:	Utility			
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File Listing:

Document Number	Document Description	File Name	File Size(Bytes)	Multi Part /.zip	Pages (if appl.)
1	Amendment After Final	AB-1350US_AMEND.pdf	147846	no	5
Warnings:					

Information:		
	Total Files Size (in hytes):	147846

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New Applications Under 35 U.S.C. 111

If a new application is being filed and the application includes the necessary components for a filing date (see 37 CFR 1.53(b)-(d) and MPEP 506), a Filing Receipt (37 CFR 1.54) will be issued in due course and the date shown on this Acknowledgement Receipt will establish the filing date of the application.

National Stage of an International Application under 35 U.S.C. 371

If a timely submission to enter the national stage of an international application is compliant with the conditions of 35 U.S.C. 371 and other applicable requirements a Form PCT/DO/EO/903 indicating acceptance of the application as a national stage submission under 35 U.S.C. 371 will be issued in addition to the Filing Receipt, in due course.